

## F-6971

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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Seiichi HAYASHI, et al.

Serial No.

09/852,111

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For

METHOD AND APPARATUS FOR MEASURING

THIN FILM, AND THIN FILM DEPOSITION

**SYSTEM** 

Group Art Unit

2882

Examiner

Hoon K. Song

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Form PTO-1449 U.S. Department of Commerce Atty. Docket No.: F-6971 Serial No.: 09/852,111 (Rev. 7-80) Patent and Trademark Office Applicant: Seiichi HAYASHI, et al. 42-44F (F-49) INFORMATION DISCLOSURE CITATION Group: 2882 Filing Date: May 9, 2001 (Use several sheets if necessary) **U.S. PATENT DOCUMENTS** Date Class Filing Date Examiner **Document Number** Name **Subclass** Initial Appropriate FOREIGN PATENT DOCUMENTS Date Country Class **Subclass Translation Document Number** Yes No TRANSLATION KEY: \* English Abstract. F Concise statement of relevance provided in foreign search report. Concise statement of relevance provided in specification. Concise statement of relevance provided in IDS. Relevant portion of reference translated. English abstract only - copy of reference in pct search. OTHER INFORMATION DISCLOSURE CITATIONS (Including Author, Title, Date, Pertinent Pages, Etc.) 1997 - X-ray Reflectometer for the Diagnostics of Thin Films During Growth, U. Niggemeier, K. Lischka, W. M. Plotz and V. Holy, Journal of Applied Crystallography, Volume 30, Pages 905-908 DATE CONSIDERED **EXAMINER** Hoon K. Song EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.